

SUBSTRATE FILM THICKNESS MEASUREMENT METHOD,
SUBSTRATE FILM THICKNESS MEASUREMENT APPARATUS
AND SUBSTRATE PROCESSING APPARATUS

ABSTRACT OF THE DISCLOSURE

5 A jet of water in a cylindrical form is supplied from
a jet nozzle onto a measurement surface of a substrate to
form a column of the water extending between the nozzle and
the measurement surface. Light is emitted from an
irradiation fiber and transmitted through the column of
10 water to the measurement surface. The light reflected by
the measurement surface is received by a light-receiving
fiber through the column of water. A measurement
calculation unit measures the thickness of a film formed on
the substrate, based on the intensity of the reflected
15 light.